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- Docket: 0756-575

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of)
TAKASHI INUSHIMA et al)

Serial No. 07/702,492) Art Unit 134

Filed: May 20, 1991) Examiner G. Goudreau

For: CVD APPARATUS)

AMENDMENT

Honorable Commissioner of Patents and Trademarks Washington, D.C. 20231

Sir:

In response to the Office Action mailed July 29, 1991, please amend the above-identified patent application as follows:

In the Claims:

Please amend claims 1-3 as follows:

1. (Amended) A method for forming a film comprising the steps of:

placing a substrate in a reaction chamber;

introducing a reactive gas <u>comprising tetra-ethyl-</u> <u>oxy-silane</u> into said reaction chamber;

inputting an <u>optical</u> energy for activating said reactive gas; and

depositing a silicon-dontaining compound on said substrate,

wherein said [reactive gas comprises tetra-ethyloxy-silane] optical energy is light emitted by a mercury lamp.

2. (Amended) [The method of claim 1 wherein said energy is an electromagnetic energy] A method for forming a film comprising the steps of:

placing a substrate in a reaction chamber;
introducing a reactive gas comprising tetra-ethyl100 DH 01/10/92 07702492
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